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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/636,132	08/06/2003	Craig A. Hickman	108298728US	2394
25096	7590	07/24/2006	EXAMINER	
PERKINS COIE LLP			STINSON, FRANKIE L	
PATENT-SEA				
P.O. BOX 1247			ART UNIT	
SEATTLE, WA 98111-1247			PAPER NUMBER	
			1746	

DATE MAILED: 07/24/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

1. In view of the cancellation of claim 22-55, the Restriction Requirement dated April 14, 2006 is hereby vacated.

2. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

3. Claims 1-3, 8-15 and 19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Imai (U. S. Pat. No. 6,624,879) in view of either Shirley et al. (U. S. Pat. No. 6,817,057) or Japan'261 (Japan.10-294161)

Re claims 1, 11 and 18, Imai is cited disclosing a stepper or scanner machine for processing microfeature workpieces, the machine comprising: a housing (not shown); an illuminator (IL) disposed within the housing; a lens (21) disposed within the housing; a workpiece support (1) disposed within the housing; a cleaning device disposed within the housing to remove contaminants from the workpiece support (see col. 14, lines 59 thru col. 14, line 5); and a stage (27, 28) carrying the workpiece support that differs from the claims only in the recitation of at least one of the stage and the cleaning device being movable relative to the other to selectively position the workpiece support at least proximate to the cleaning device. The patents to Shirley and Japan'261 are each cited disclosing in a device to clean a chuck, the arrangement of providing relative movement between the cleaning device and the workpiece. It therefore would have been obvious to one having ordinary skill in the art to modify the arrangement of Imai, to have relative movement between the workpiece support and the cleaning device for the purpose of

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positioning the chuck and cleaning device for proper cleaning. Re claim 2, Imai disclose the end effector (29). Re claim 13 and 19, Japan'261 and Shirley disclose the distal end effector. Re claim 8-10, Imai discloses the controller to perform a cleaning in that Imai discloses that "apparatus initiate a suitable cleaning sequence operation", col. 14, lines 1-4)

4. Claims 5, 6, 16, 17, 20 and 21 are rejected under 35 U.S.C. 103(a) as being unpatentable over the applied prior art as applied to claims 1, 11 and 18 above, and further in view of Morgan (U. S. Pat. No. 6,290,863) or Gindel (U. S. Pat. No. 6,666,927) or Japan'400 (Japan 5-291400).

Claims 5, 6, 16, 17, 20 and 21 define over the applied prior art only in the recitation of the vacuum means for removing the contaminants. Morgan, Gindel and Japan'400 are each cited disclosing an arrangement of providing vacuum means for removing contaminants. It therefore would have been obvious to one having ordinary skill in the art to modify the apparatus of Imai, to include vacuum removing means as taught by Morgan, Gindel, or Japan'400, for the purpose of preventing the contaminants from being re-deposited back onto the just cleaned surface. Also note that Morgan discloses the second cleaning fluid passageway.

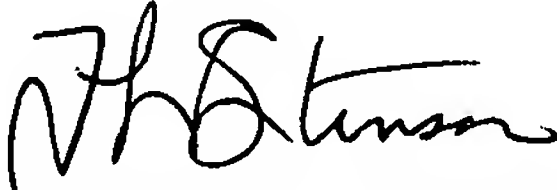
5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. In Hiatt et al., Matsui, Japan'627, Japan'762, japan'930, Japan'740, Nakazawa et al., Korean'808, Sato et al., Ohmi et al., Chiou, Aiyer et al. and Japan'827, note the cleaning means.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to FRANKIE L. STINSON whose telephone number is (571) 272-1308. The examiner can normally be reached on M-F from 5:30 am to 2:00 pm and some Saturdays from approximately 5:30 am to 11:30 am.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Michael Barr, can be reached on (571) 272-1700. The fax phone number for the organization where this application or proceeding is assigned is 571-272-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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FRANKIE L. STINSON
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GROUP ART UNIT 1746